

PROJECT 33034



MODEL S1000CRCS-70

FEATURING Interchangeable End-Effectors, Articulated Arm with Positional Brakes, Overload/Obstacle Encounter Protection, Deployable Outriggers with Stability Interlocks, Powered Drive, ISO 5 (Class 100) Cleanroom, SEMI S2 & CE Compliant

HANDLING 125lb [57 kg] Wet Tanks

DETAILS Wafer cleaning is a critical step in manufacturing semiconductors. Servicing these tools in a safe and timely manner allows manufacturers to produce high yield wafers. This cleanroom lift is uniquely suited to work in a narrow aisle while still meeting reach and stability requirements. The multi-purpose design allows different end-effectors to be attached to an articulated arm for handling components such as wet tanks, door plates and robots.

